

技术及应用

## CMOS器件辐照后热退火过程中激发能分布的确定

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**摘要** 对CMOS晶体管辐照后的等温、等时退火特性进行讨论, 给出辐照敏感参数在等温、等时退火过程中随退火时间、退火温度的变化关系。根据退火模型计算了CMOS器件辐照后25、100 °C等温和25~250 °C等时退火过程中激发能的分布。结果表明: 25、100 °C等温退火激发能范围分别在0.65~0.76 eV和0.75~0.95 eV之间; 25~250 °C等时退火的激发能范围在0.5~1.1 eV之间, 峰值位于0.81 eV。

关键词

[等时退火](#) [等温退火](#) [激发能](#)

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## Determination of Activation Energy Distribution During Thermal Annealing in Post-Irradiation CMOS Devices

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### Abstract

The annealing characteristics of isothermal and isochronal for post-irradiation CMOS transistor are discussed. The relations about radiation sensitive parameters with isothermal annealing time and isochronal annealing temperature are given. The activation energy distribution during 25, 100 °C isothermal annealing and 25-250 °C isochronal annealing for post-irradiation CMOS devices are calculated by annealing model. According to the result, the range of activation energy for isothermal annealing at 25, 100 °C is from 0.65 eV to 0.76 eV and from 0.75 eV to 0.95eV respectively. The range of activation energy for isochronal annealing at 25-250 °C is from 0.5 eV to 1.1 eV.

**Key words** [isothermal annealing](#) [isochronal annealing](#) [activation energy](#)

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